

Guojin Chen

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Publications [Google Scholar; 61+ citations, h-index: 4+]

Representative publications that I am a primary author on are highlighted.

- [C10] *Physics-Informed Optical Kernel Regression Using Complex-valued Neural Fields*
Guojin Chen, Zehua Pei, Haoyu Yang, Yuzhe Ma, Bei Yu, and Martin Wong
DAC 2023
- [C9] *DiffPattern: Layout Pattern Generation via Discrete Diffusion*
Zixiao Wang, Yunheng Shen, Wenqian Zhao, Yang Bai, Guojin Chen, Farzan Farnia, and Bei Yu
DAC 2023
- [C8] *GPU-accelerated Matrix Cover Algorithm for Multiple Patterning Layout Decomposition*
Guojin Chen, Haoyu Yang, and Bei Yu
SPIE 2023
- [C7] *OpenILT: An Open-source Platform for Inverse Lithography Technology Research*
Su Zheng, Yuzhe Ma, Binwu Zhu, Guojin Chen, Wenqian Zhao, Shuo Yin, Ziyang Yu, and Bei Yu
GitHub 2023
- [C6] *Efficient Point Cloud Analysis Using Hilbert Curve.*
Wanli Chen, Xinge Zhu, Guojin Chen, and Bei Yu
ECCV 2022
- [C5] *AdaOPC: A Self-Adaptive Mask Optimization Framework For Real Design Patterns*
Wenqian Zhao, Xufeng Yao, Ziyang Yu, Guojin Chen, Yuzhe Ma, Bei Yu, and Martin Wong
ICCAD 2022
- [C4] *DevelSet: Deep Neural Level Set for Instant Mask optimization*
Guojin Chen, Ziyang Yu, Hongduo Liu, Yuzhe Ma, and Bei Yu
ICCAD 2021
- [C3] *Learning Point Clouds in EDA.* (Invited Paper)
Wei Li, Guojin Chen, Haoyu Yang, Ran Chen, and Bei Yu
ISPD 2021
- [C2] *DAMO: Deep Agile Mask Optimization for Full Chip Scale*
Guojin Chen, Wanli Chen, Yuzhe Ma, Haoyu Yang, and Bei Yu
ICCAD 2020
- [C1] *A GPU-enabled Level Set Method for Mask Optimization*
Ziyang Yu, Guojin Chen, Yuzhe Ma, and Bei Yu
DATE 2020

Professional Activities

Design Automation Conference (DAC)	2023
AAAI Conference on Artificial Intelligence (AAAI)	2022
IEEE Transactions on Computer-Aided Design of Integrated Circuits and Systems (TCAD)	2022-2023

Reviewing.....

Teaching

Python Computing (AIST 1110), TA	F2022
Mobile Computing (CSCI 3310), TA	S2022
Numerical Optimization (AIST 3010), TA	F2021